

Top Level Functional Requirements for Lithium Thin Film System

- **Enable thin film R&D with various fluids:**
 - Lithium
 - Water
 - Possibly others:
 - Ga
 - FC3283

- **Argon pressure driven flow to:**
 - Handle all above fluids
 - Eliminate need for pump

- **Test loop physical parameters**
 - Maximum vertical space = 96"
 - Maximum footprint = 30" X 30"
 - Select radiant heaters to melt Li
 - Maximum 30 amp zones available = 6
 - Maximum available power to a single zone = 30 amps at 208 volts
 - Maximum 50 amp zones available = 2
 - Maximum available power to a single zone = 50 amps at 208 volts
 - Design exterior thermal shield to enclose the entire test loop
 - Thermal shield box must encompass all heaters but allow openings for view and beam ports
 - Thermal shield box must allow openings for pneumatic and manual valve actuator access outside of the thermal shield
 - Thermal shield box must allow openings for power leads and TC cables
 - All pressure sensors and transducers to be located outside of Thermal shield box
 - Main vacuum connection to pumping system to be a QF 50 connection
 - Vacuum lines inside thermal shield must be Cajon or Conflat type for high temperature

- **Nozzle assembly:**
 - Nozzle easily removable (only performed at room temperature)
 - Maximum weight of removable components = 20 lb

- **Minimize quantity of Li requiring disposal as part of nozzle change out**
 - Minimize Li wetted surface area exposed to air during nozzle change operation
 - Maximum cleanable component footprint = 18" X 10"
 - Maximum cleanable component height = 15"
- **Allow course adjustment of impingement angle wrt plate +- TBD°**
- **At operating temperature:**
 - Allow easy fine adjustment of impingement angle wrt plate +- 5°
 - Allow easy adjustment of distance between nozzle exit & impingement plate

- **Allow visual observation of film**
 - Digital still & video cameras
 - Maximum view port height = 66"
 - Minimum view port height = 46"

- **Instrumentation:**
 - TCs
 - Sight glass for ΔP vs flow calibration (not used with Li)
 - Ruler or other measurement markings for film width determination
 - Gas pressure transducer
 - Vacuum gauges
 - Electron gun film thickness system (developmental)

- **Allow testing of rotating disk as a possible means of**
 - Increasing and controlling film speed
 - Controlling film thickness

- **Li purification**
 - Replace impure Li inventory with fresh Li
 - Install replaceable large surface area, 10 μm SS filter in pressure line